Metrological Characterization of a Sensitive Secondary Ion Mass Spectrometer for Electron Microscopes to Combine Optical/Structural and Analytical Imaging

<u>Alexander Laue</u>, Albrecht Glasmachers, Albrecht Brockhaus; University of Wuppertal, Germany

Introduction

Overview:

In many applications the combination of optical/structural and analytical imaging of the same target at the same time is desirable. In an electron microscope a focused electron beam is used for optical imaging. For nano-scale surface processing and advanced structural imaging a primary focused ion beam (FIB) is used. The FIB produces a small amount of secondary ions, which can be used for spatially resolved mass spectrometry.

Challenges:

- Limited space
- Low secondary ion beam currents (typical 1 ... 5 pA)
- Broad kinetic energy distribution of the secondary ions
- Difficult vacuum conditions

Approach:

- Helium cooling section to minimize energy distribution width
- Extraction lens configuration [1]
- Axial segmented linear quadrupole trap made in planar technology [2] for ion transfer
- Pressure stage incorporating a quadrupole ion wave guide for ion transfer between different pressure regions
- 3D-Ion trap used in Fourier Transform mode as mass analyzer



Compact and fully integrated SIMS-device







Michel Aliman, Hubert Mantz; Carl Zeiss NTS GmbH, Oberkochen, Germany



University of Wuppertal, Germany Institute for Pure and Applied Mass Spectrometry